

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

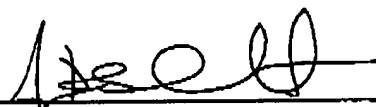
Application Serial No. 10/820,575
Filing Date April 7, 2004
Inventor Scott E. Moore et al.
Assignee Micron Technology, Inc.
Group Art Unit 2877
Examiner Roy Punnoose
Attorney's Docket No. MI22-2493
Title: Semiconductor Workpiece Processing Methods and Turbidity Monitoring Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 11/16/06By: 
James D. Shaurette
Reg. No. 39,833

Sheet 1 of 1

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| Form PTO-1449 | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | | ATTY. DOCKET NO. MI22-2493 | | SERIAL NO. 10/820,575 | |
| LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) | | | | | APPLICANT Scott E. Moore et al. | | | |
| | | | | | FILING DATE April 7, 2004 | | GROUP 1734 | |
| U.S. PATENT DOCUMENTS | | | | | | | | |
| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate | |
| | AA | 5,865,665 | 2/2/1999 | Yueh | | | | |
| | AB | 5,207,921 | 5/4/1993 | Vincent, John D. | | | | |
| | AC | 3,809,243 | 5/7/1974 | Teders, Phillip J. | | | | |
| | AD | | | | | | | |
| | AE | | | | | | | |
| | AF | | | | | | | |
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| | AM | | | | | | | |
| | AQ | | | | | | | |
| FOREIGN PATENT DOCUMENTS | | | | | | | | |
| | | Document Number | Date | Country | Class | Subclass | Translation | |
| | | | | | | | Yes | No |
| | AR | | | | | | | |
| | AS | | | | | | | |
| | AV | | | | | | | |
| OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | | |
| EXAMINER | | | | | DATE CONSIDERED | | | |
| <p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p> | | | | | | | | |